



IPW

PATENT  
8045-1015

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Shinichi NAKATA et al.

Conf. 6017

Application No. 10/676,132

Group 1725

Filed October 2, 2003

Examiner Maria A. Elve

MASK FOR LIGHT EXPOSURE AND METHOD  
FOR MANUFACTURING LIQUID CRYSTAL  
DISPLAY APPARATUS EMPLOYING SAME

RESPONSE

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 18, 2006

Sir:

This responds to the Official Action of October 18,  
2005.

**Remarks** begin on page 2 of this paper.